

ATTY DKT. No.:
U.S. SERIAL No.:
FILED:
APPLICANT:
TITLE:

AMAT/5619/DSM/LOW K/JW
09/012,103
JUN 23, 2001
APPLIED MATERIALS, INC.
SELECTIVE ETCHING OF ORGANOSILICATE FILMS OVER
SILICON OXIDE STOP ETCH LAYERS
NGUYEN, ET AL.

CONF. No.: 447

INVENTOR:
EXPRESS MAIL No.: N/A

PAGE 1 of 6

1/6

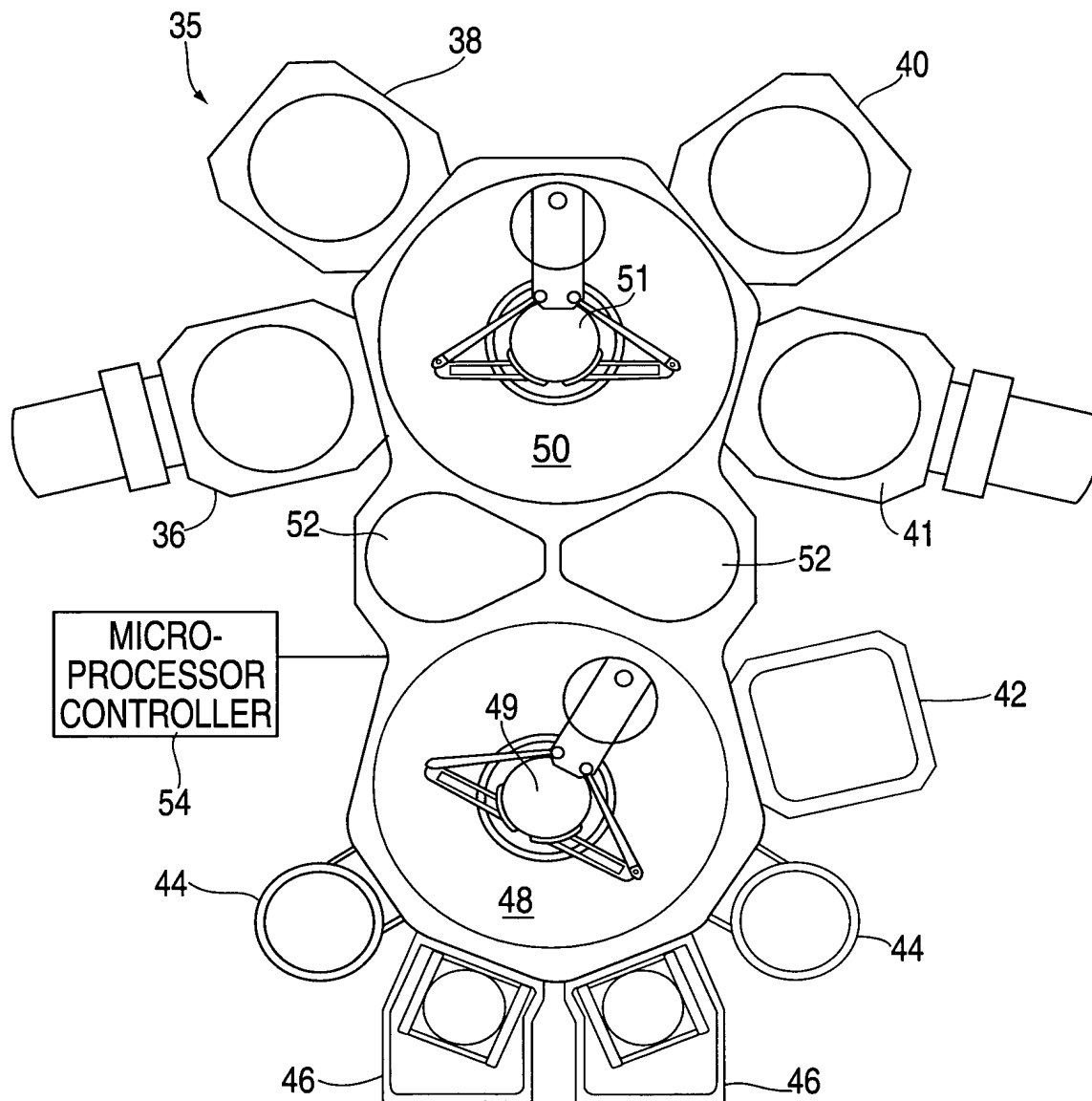


FIG. 1

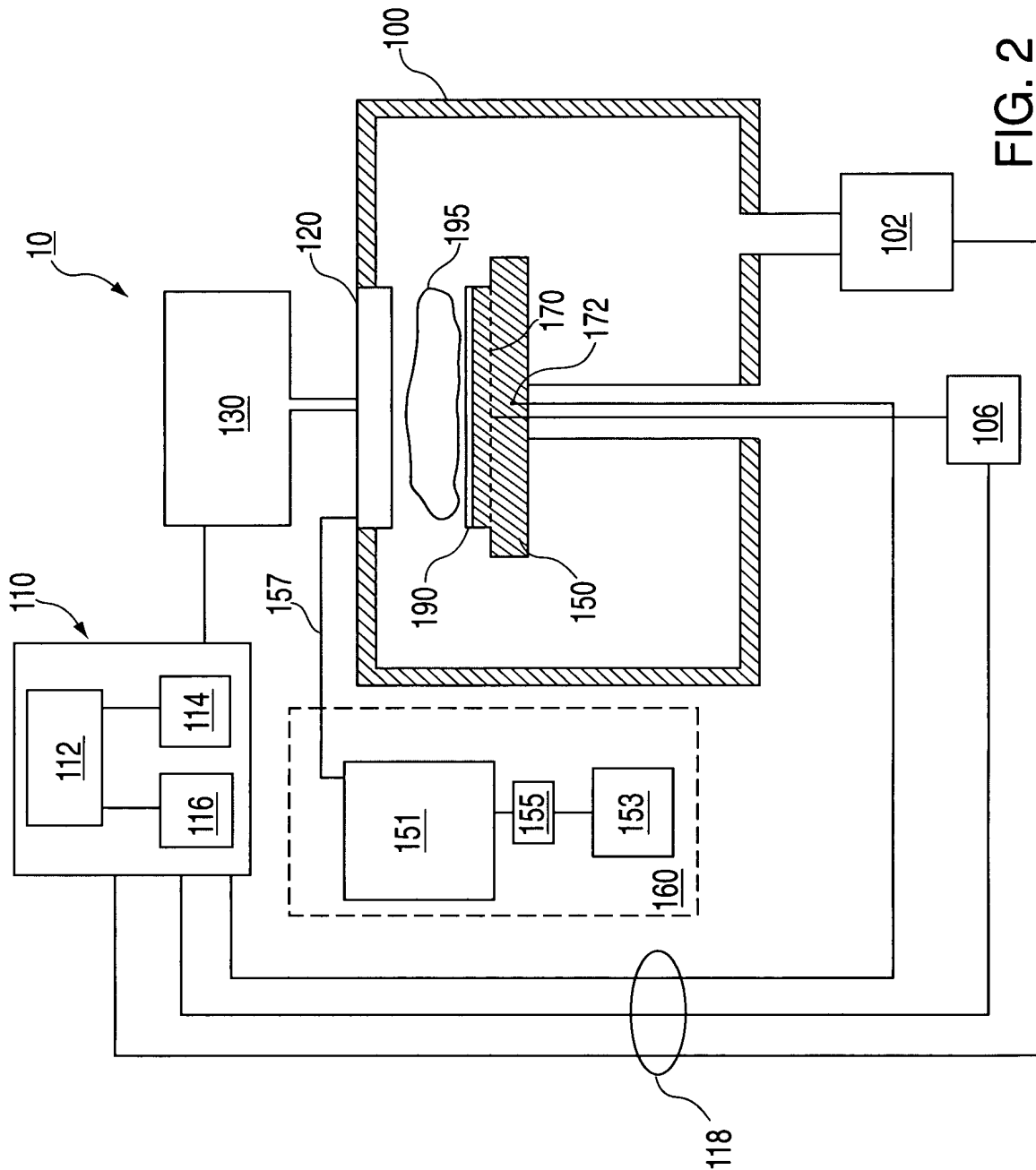


ATTY DKT. NO.: AMAT/5619/DSM/LOW K/JW
U.S. SERIAL NO.: 09/912,103
FILED: JULY 23, 2001
APPLICANT: APPLIED MATERIALS, INC.
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SILICON OXIDE STOP ETCH LAYERS
INVENTOR: NGUYEN, ET AL.
EXPRESS MAIL NO.: N/A

CONF. NO.: 4476

PAGE 2 of 6

2/6



3/6

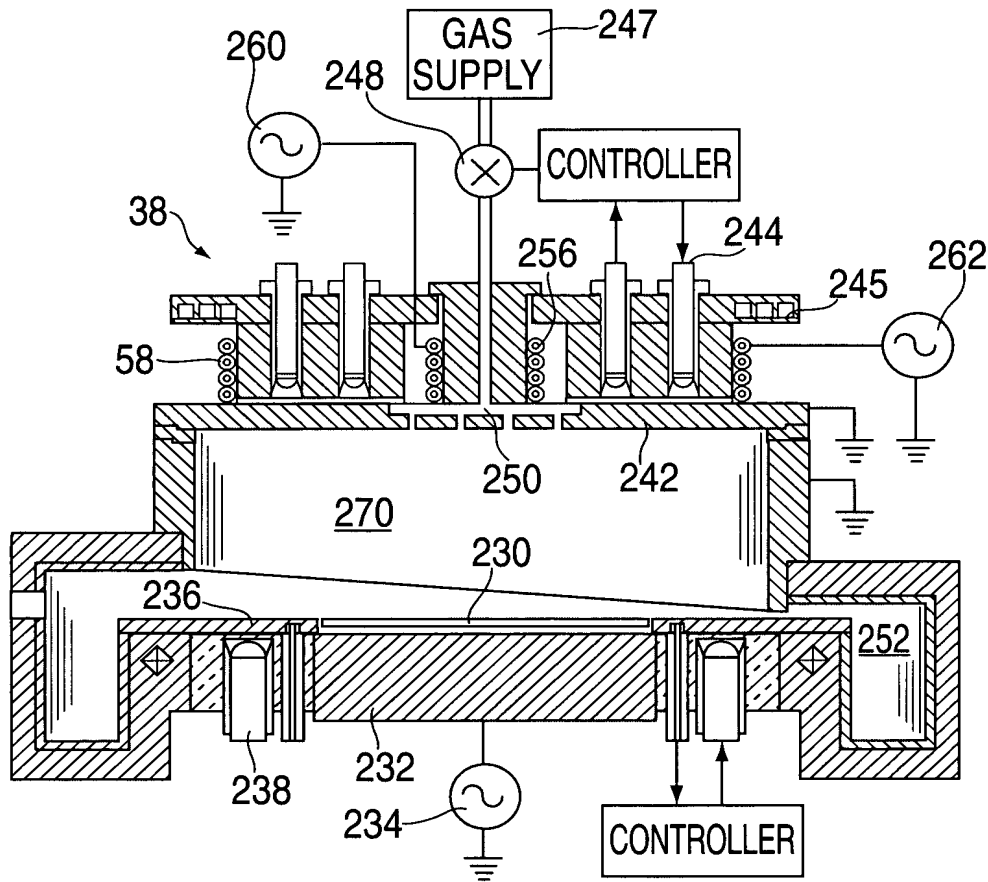


FIG. 3



4/6

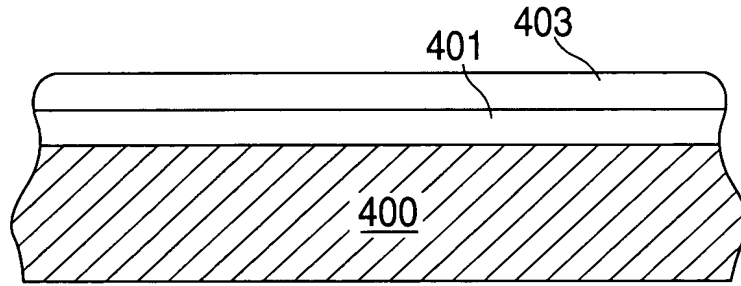


FIG. 4a

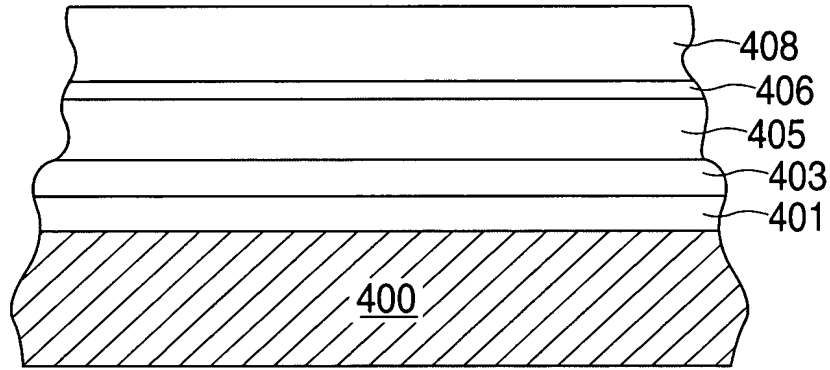


FIG. 4b

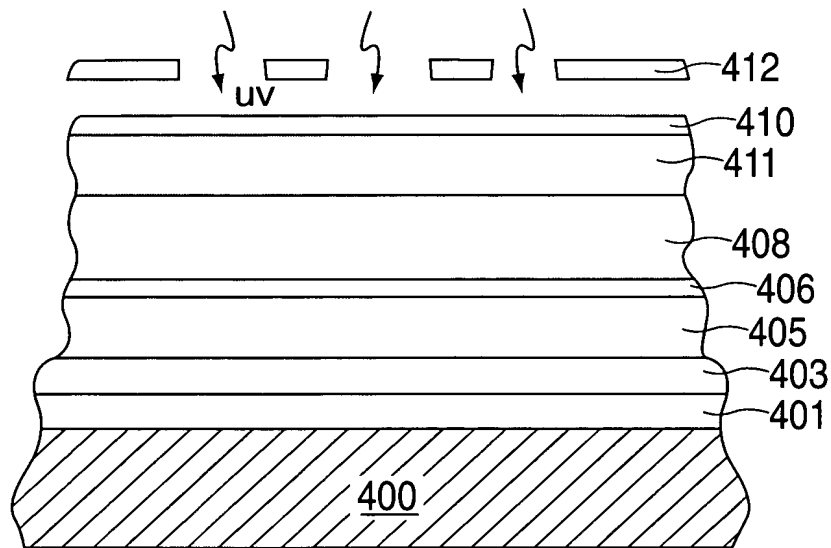


FIG. 4c



5/6

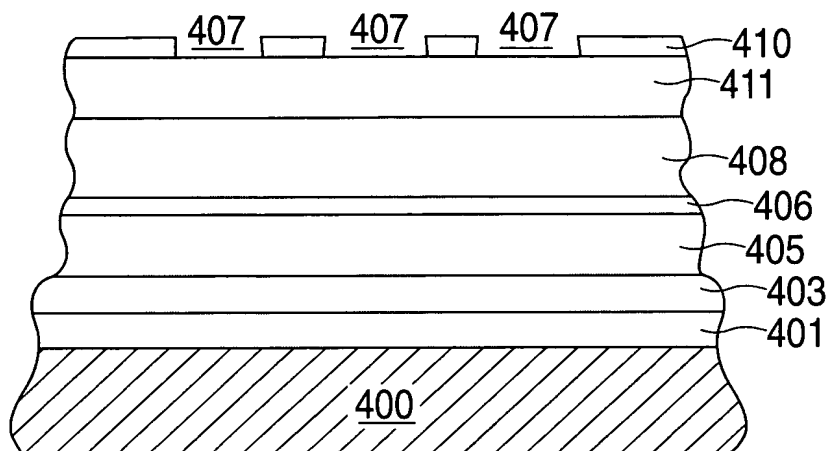


FIG. 4d

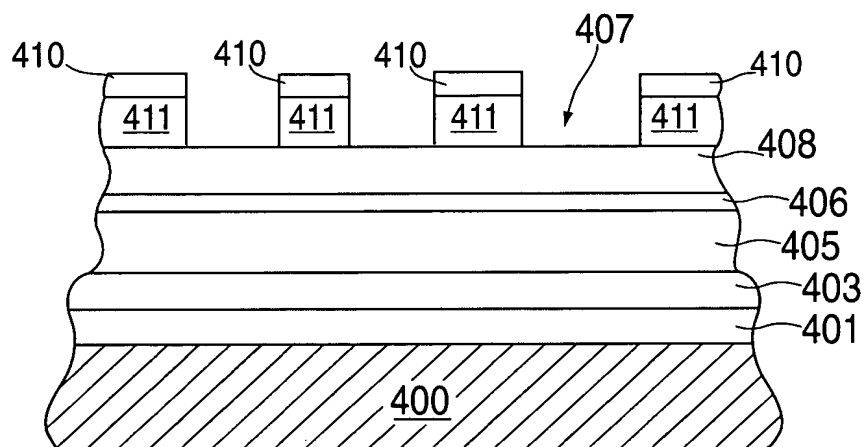


FIG. 4e



6/6

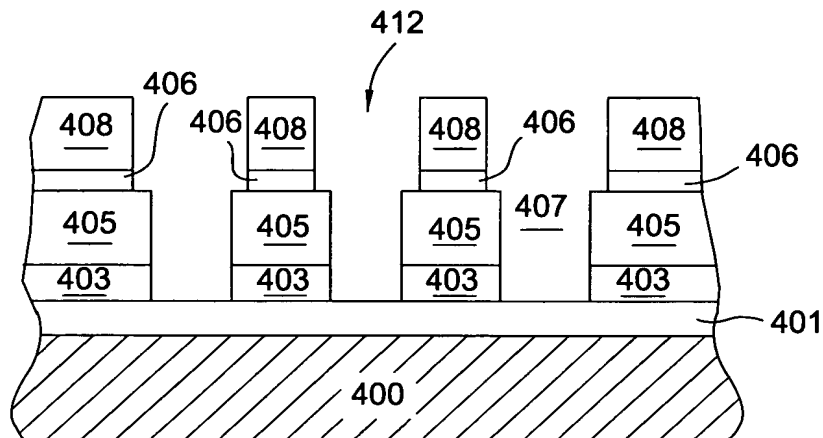


FIG. 4F

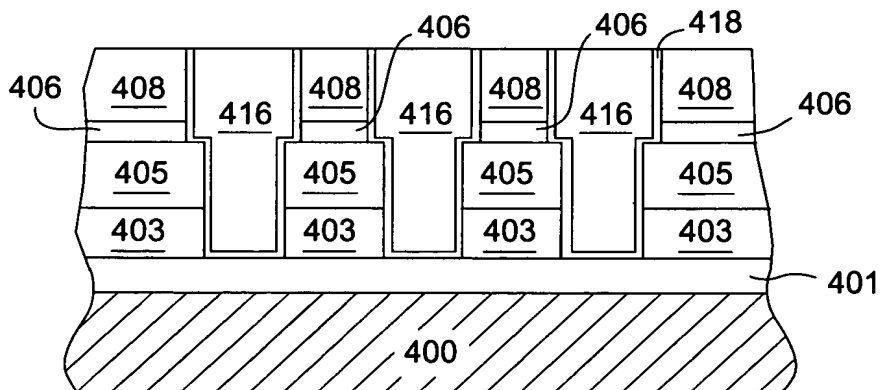


FIG. 4G